

# ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Stylesheet Version v18.0

## Title of Invention

APPARATUS AND METHOD FOR MANIPULATING SAMPLE  
TEMPERATURE FOR FOCUSED ION BEAM PROCESSING

Application Number :

10/711,691

Confirmation Number:

First Named Applicant:

Chad Rue

Attorney Docket Number:

FIS920040175US1

Art Unit:

2881

Examiner:


J. YANTORNO

Search string:

( 6365905 or 20040060904 or 20040112857 or 20040129879 or 20040132287 ).pr





## US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
	1	6365905	2002-04-02	KOYAMA, ET AL.			

## US Published Applications

Note: Applicant is not required to submit a paper copy of cited US Published Applications

init	Cite.No.	Pub. No.	Date	Applicant	Kind	Class	Subclass
	1	20040060904	2004-04-01	HERSCHBEIN, ET AL.			
	2	20040112857	2004-06-17	HERSCHBEIN, ET AL.			
	3	20040129879	2004-07-08	FURIKI, ET AL.			
	4	20040132287	2004-07-08	FISCHER, ET AL.			

## Signature

Examiner Name	Date
	12/28/2005